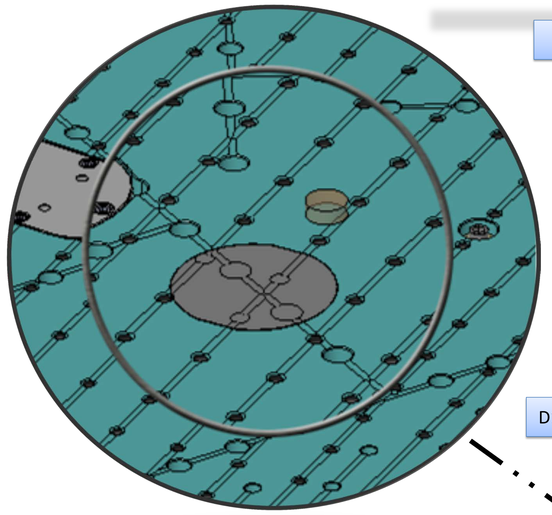
HAM ISI: WITNESS WAFERS + WITNESS OPTIC PLACEMENT



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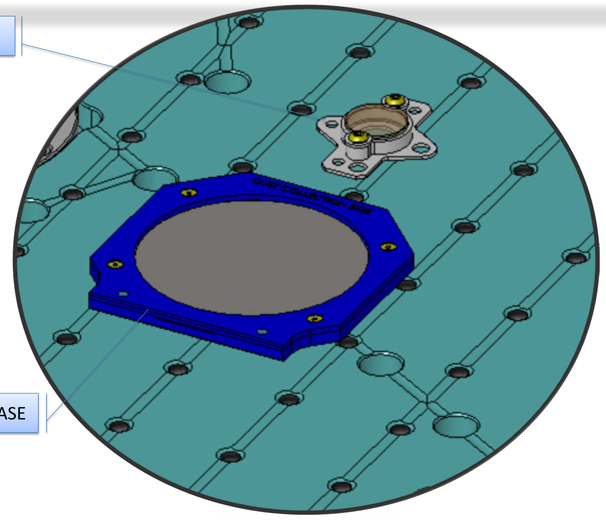
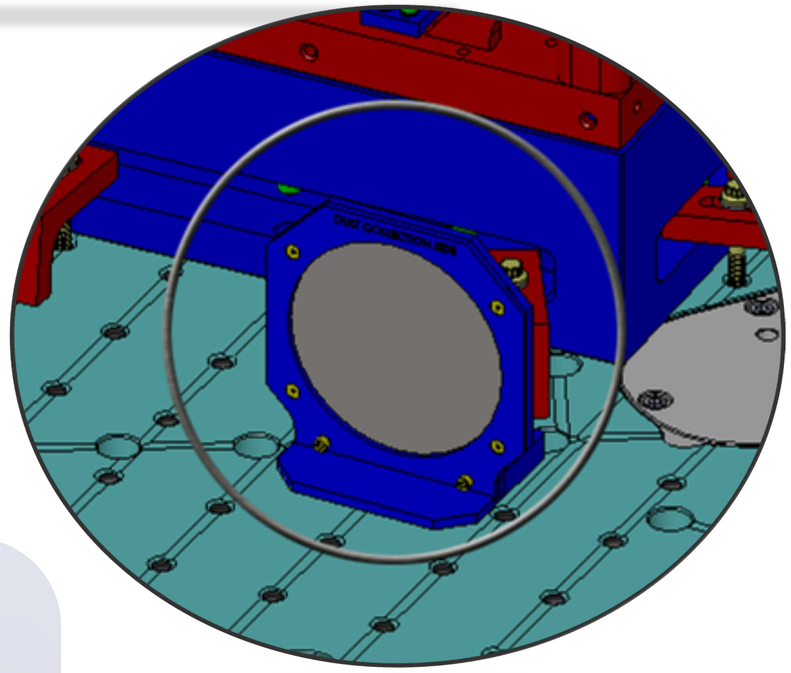


DEFAULT

PLAN B



PLAN 'B': ADD (place) Silicon Witness Wafers:

- **HORIZONTALLY: 1 X 4" SILICON WAFER (QTY. OF 1):**

Place Witness silicon wafer horizontally on or adjacent to the beam centerline (looking from above) in a convenient location. Refer to the layout of the particular chamber to determine best available location.

Indicated item on detail 'A' may be used as an alternate mounting method.

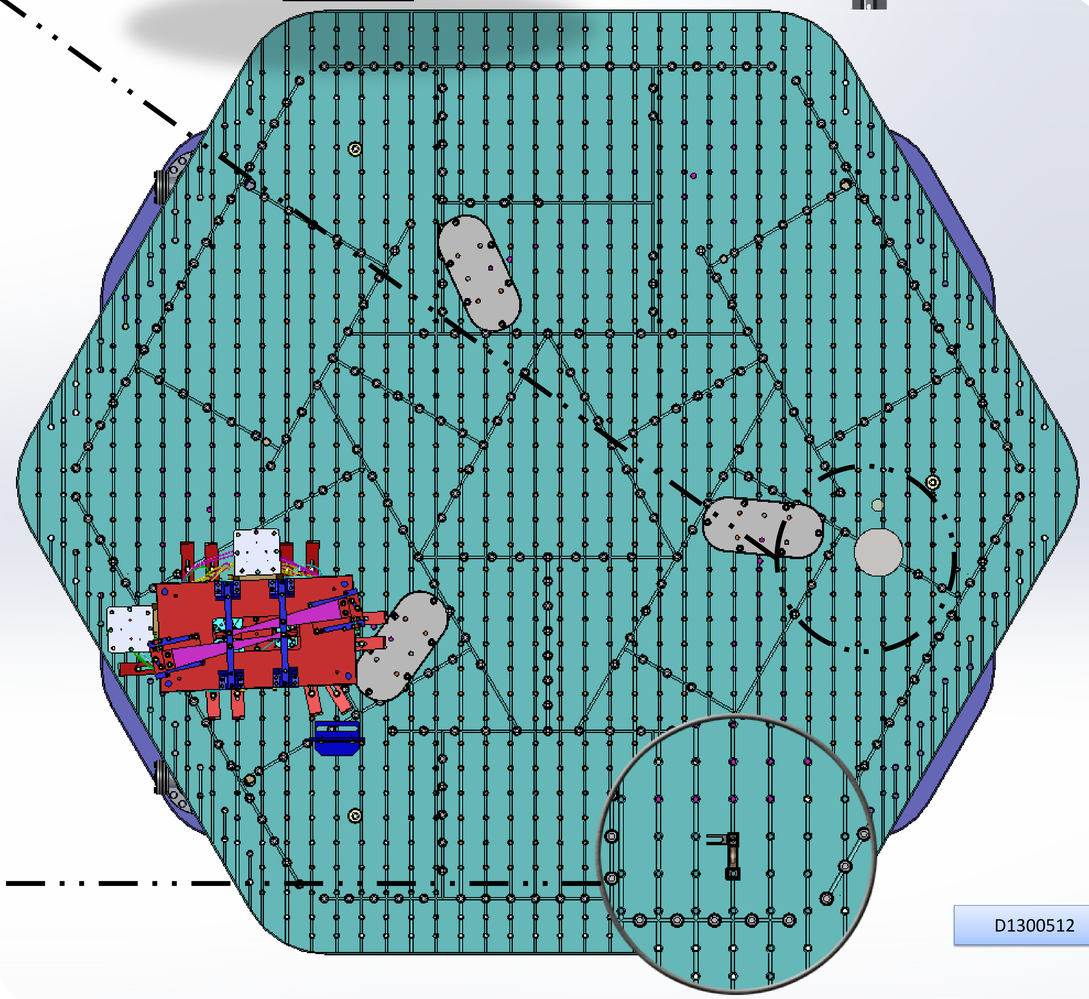
PLAN 'B : ADD (place) 1" witness optic:

- **1 X 1" OPTIC (QTY. OF 1)**:

Place with the Silicon witness wafer horizontally (HR side up) on top of the optics table. Indicated item on detail 'A' may be used as an alternate mounting method.

NOTE: AS A GENERAL RULE, PLACE WITNESSES JUST AFTER REMOVAL OF THE NEARES FIRST CONTACT. THEN REVMOE AS CLOSE TO THE NEXT CHAMBER OPENING.

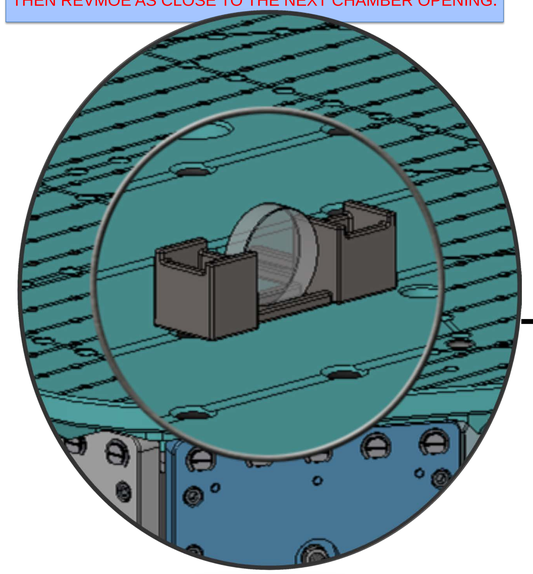
Detail 'A'

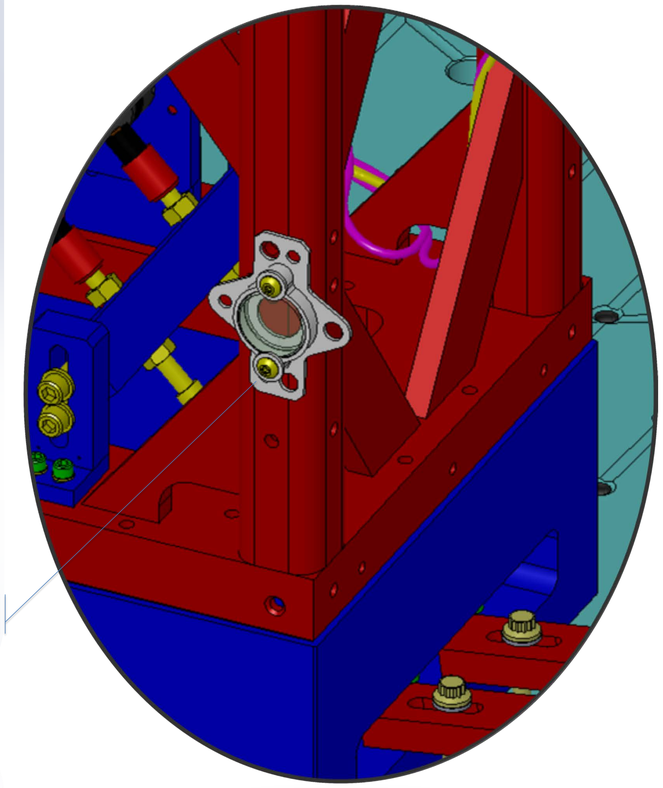


DEFAULT: ADD (place) Silicon Witness Wafer:

- **VERTICALLY: 1 X 4" SILICON WAFER (QTY. OF 1):** Place Witness silicon wafer vertically using LIGO D1300275 adjacent to HxTS structure leg, away from beams.

Refer to the layout of the particular chamber to determine best available location.





D1300512

DEFAULT

PLAN B

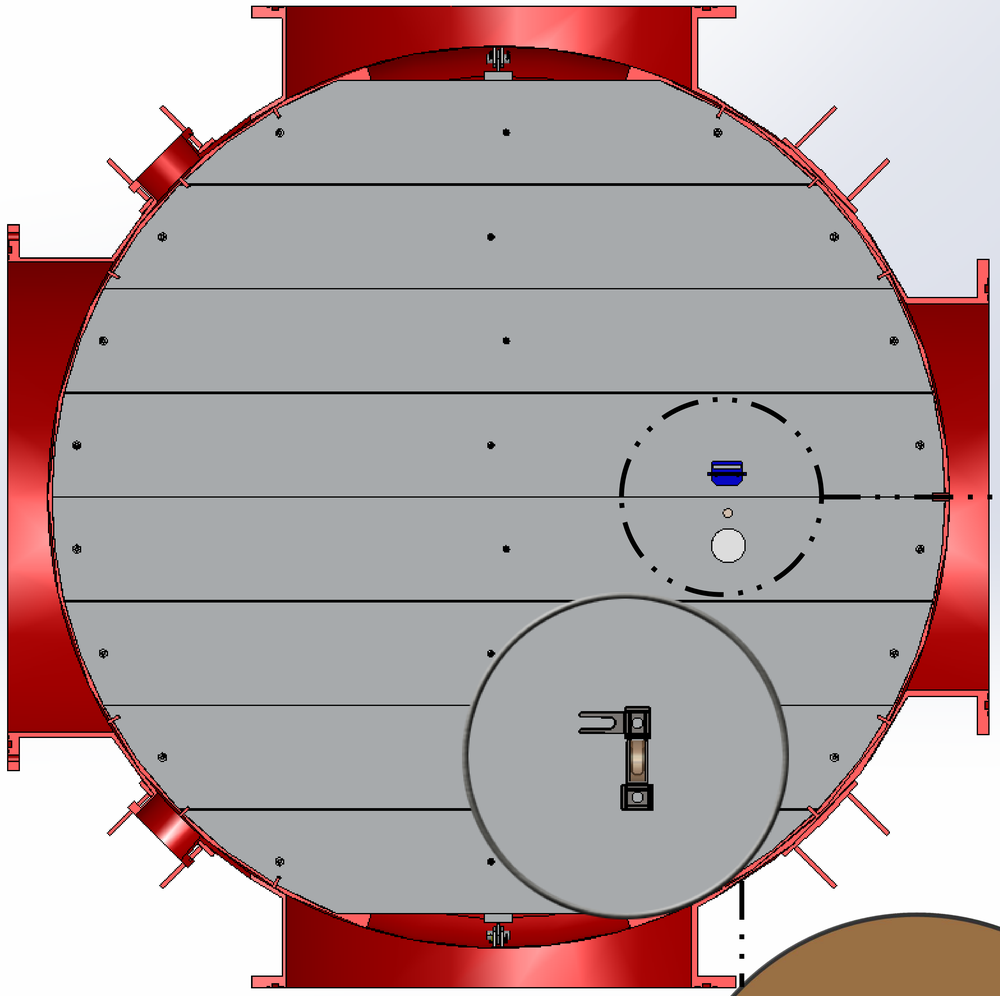
PLAN B: ADD (place) 1" witness optic:

- **1 X 1" OPTIC (QTY. OF 1)**: Place on its side, vertically as close to an optic as possible. Retain in place using a peek cable clamp as shown.

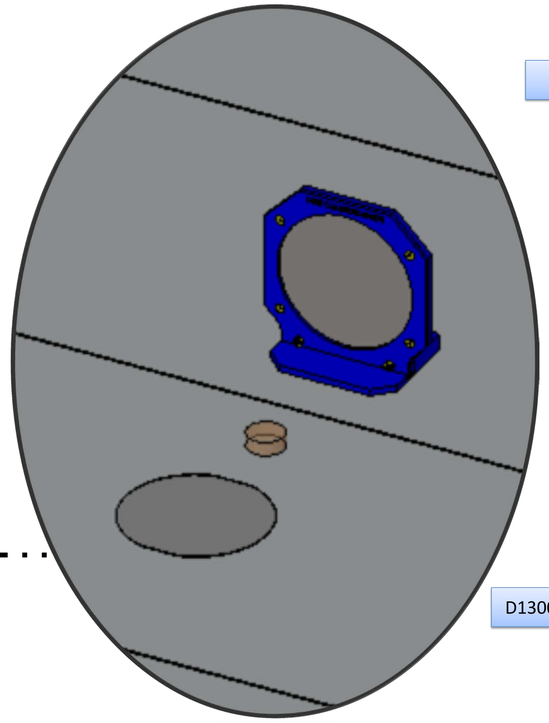
DEFAULT: ADD (place) 1" witness optic:

- **1 X 1" OPTIC (QTY. OF 1)**: Mount on HxTS structure using D1300512. Install vertically as close to an optic as possible. Retain in place using appropriate hardware

BSC FLOORING: WITNESS WAFERS + WITNESS OPTIC PLACEMENT



Detail ‘B’



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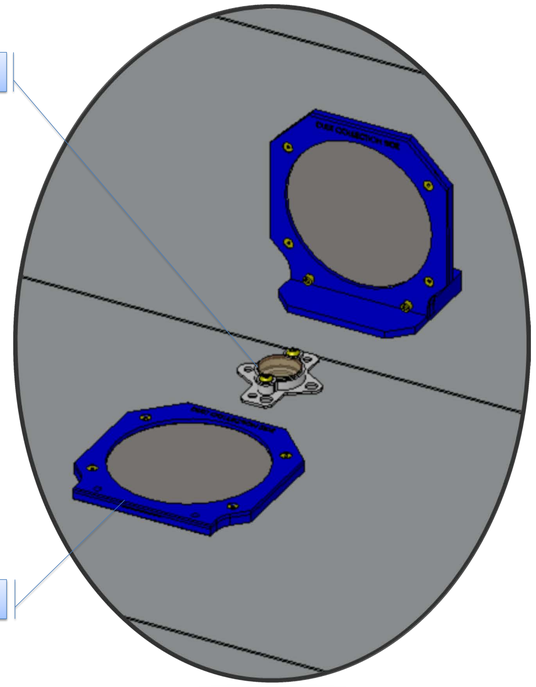
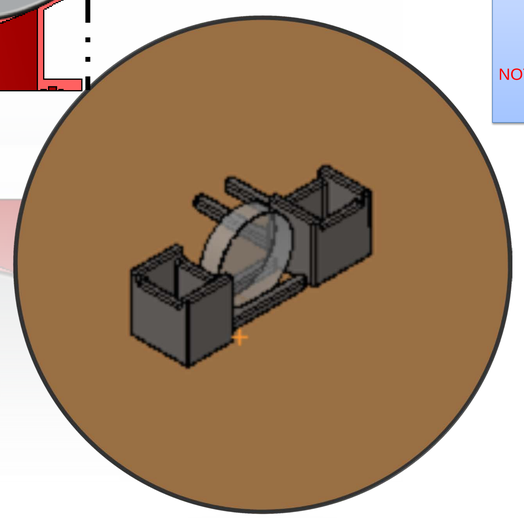




ADD (place) Silicon Witness Wafers:

- **1 X 4” SILICON WAFERS (QTY. OF 1):** Place Witness silicon wafer horizontally on or adjacent to the beam centerline (looking from above) in a convenient location. Refer to the layout of the particular chamber to determine best available location. Indicated items on detail ‘B’ may be used as an alternate mounting method.
- **1 X 4” SILICON WAFERS (QTY. OF 1):** Place Witness silicon wafer vertically away from beams using LIGO D1300275 . Refer to the layout of the particular chamber to determine best available location.

ADD (place) 1” witness optic:

- **1 X 1” OPTIC (QTY. OF 1)**: Place with Silicon witness wafers horizontally (HR side up) on top of the flooring. Indicated items on detail ‘B’ may be used as an alternate mounting method.

NOTE: AS A GENERAL RULE, PLACE WITNESSES JUST AFTER REMOVAL OF THE NEARES FIRST CONTACT. THEN REMOVE AS CLOSE TO THE NEXT CHAMBER OPENING.

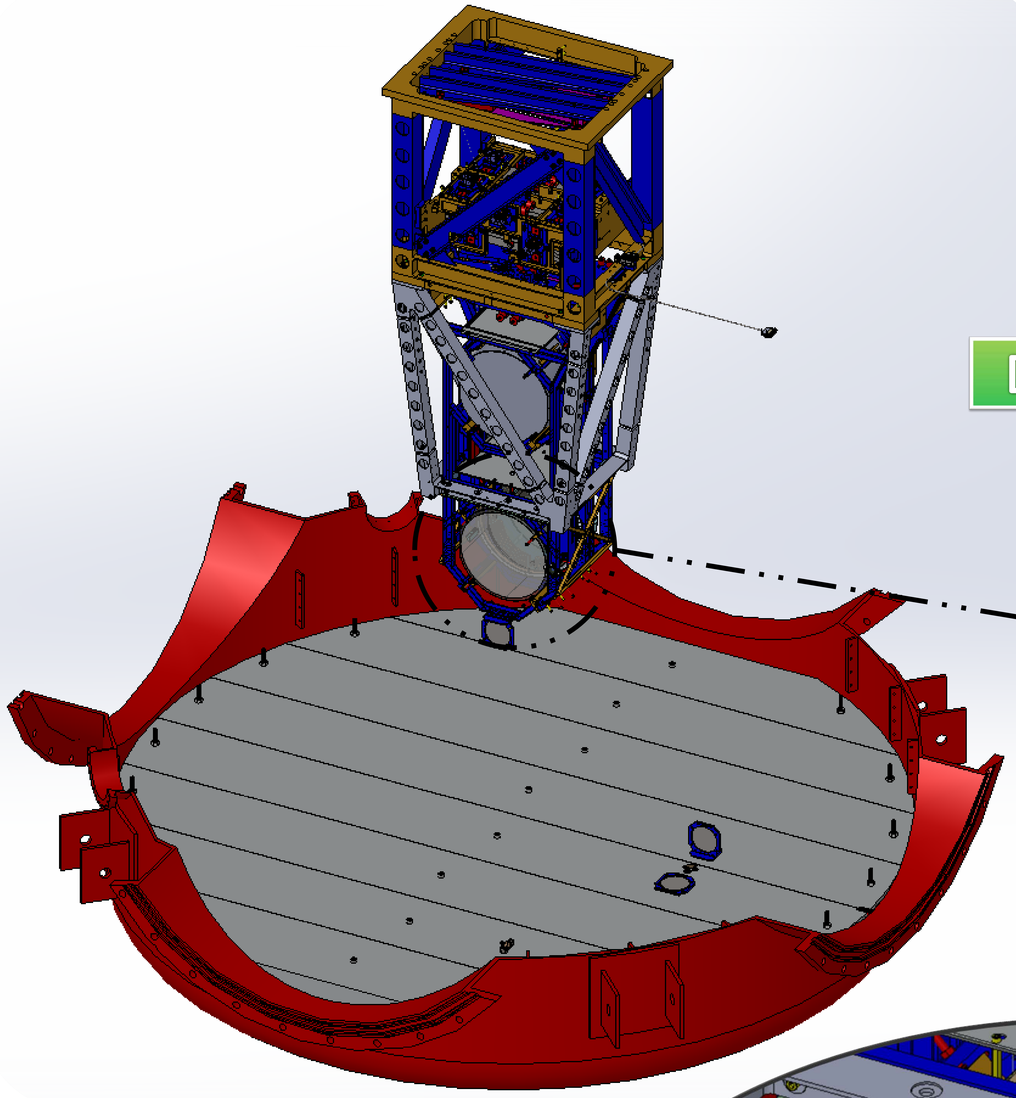
ADD (place) 1” witness optic:

- **1 X 1” OPTIC (QTY. OF 1)**: Place on its side, vertically as close to an optic as possible. Retain in place using a peek cable clamp as shown.

NOTE: SEE SHEET 3 FOR STRUCTURE MT. OPTIC

BSC PLACEMENT OPTIONS
(SEE Pg. 3 FOR PREFERRED MT. METHODS)

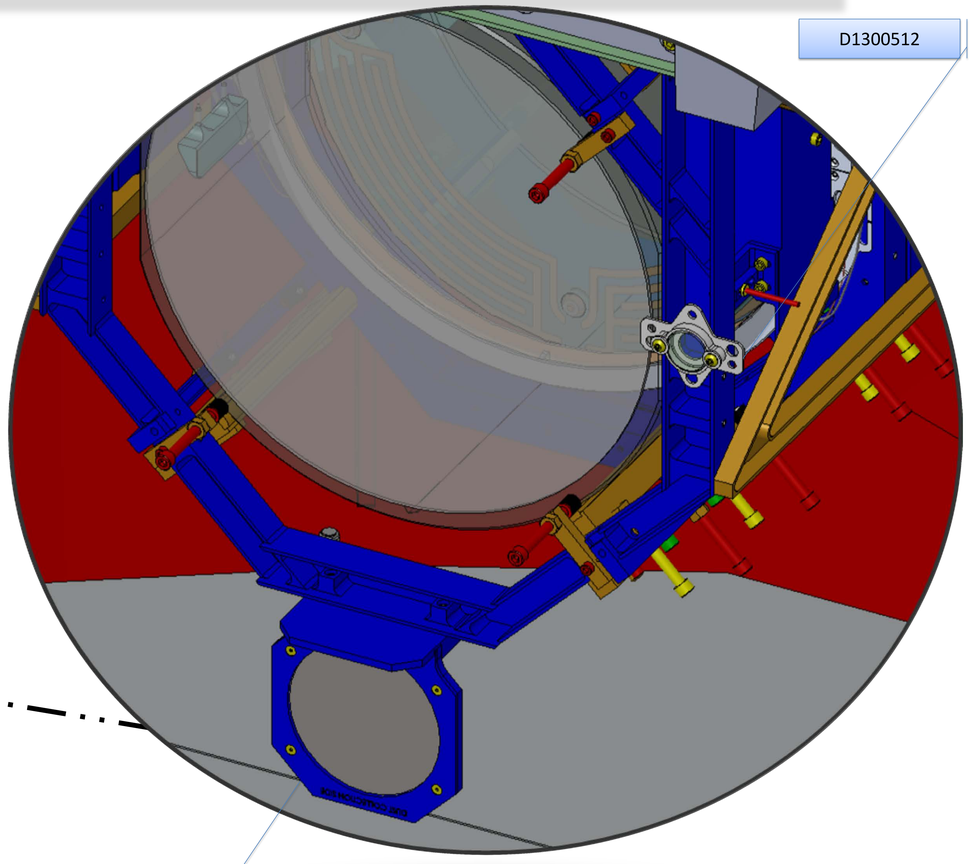
BSC: WITNESS WAFERS + WITNESS OPTIC PLACEMENT, STRUCTURE MT.



DEFAULT

OR

ALTERNATE



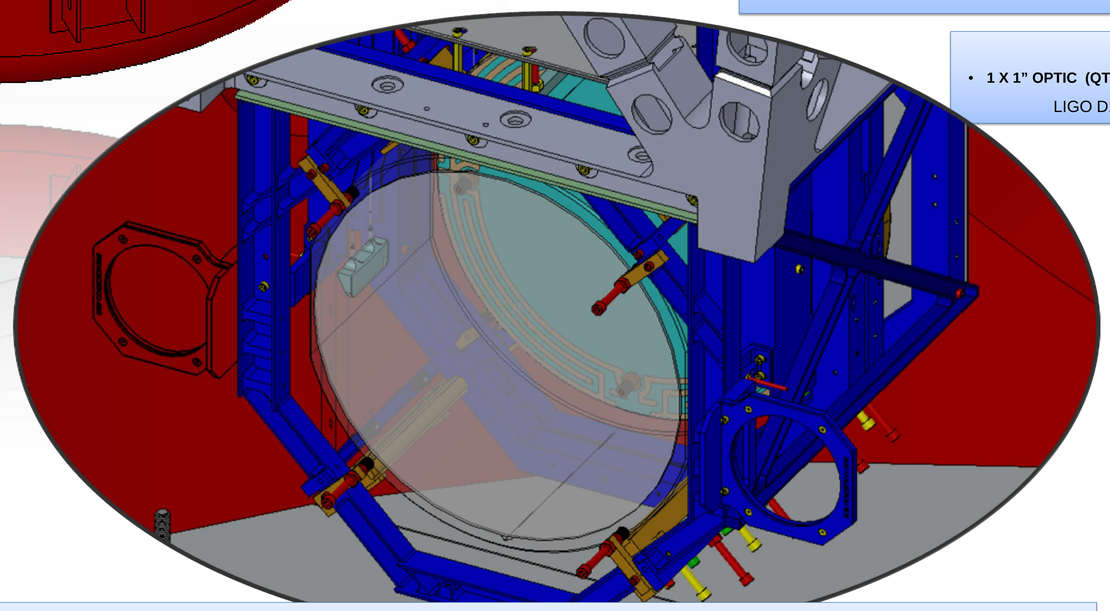
DEFAULT: **ADD (place) Silicon Witness Wafer:**

- **1 X 4” SILICON WAFERS (QTY. OF 1):** Mount Witness silicon wafer vertically as shown away from beams using LIGO D1300275 .

NOTE: AS A GENERAL RULE, PLACE WITNESSES JUST AFTER REMOVAL OF THE NEARES FIRST CONTACT. THEN REMOVE AS CLOSE TO THE NEXT CHAMBER OPENING.

ADD (place) 1” witness optic:

- **1 X 1” OPTIC (QTY. OF 1)**: Mount vertically as close to an optic as possible using LIGO D1300512. Retain in place using appropriate hardware



PLAN B: **ADD (place) Silicon Witness Wafer:**

- **1 X 4” SILICON WAFERS (QTY. OF 1):** Mount Witness silicon wafer as shown away from beams using LIGO D1300275 AT 3 OR 9 O’CLOCK POSITION .

NOTE: AS A GENERAL RULE, PLACE WITNESSES JUST AFTER REMOVAL OF THE NEARES FIRST CONTACT. THEN REMOVE AS CLOSE TO THE NEXT CHAMBER OPENING.